

MPI IMPACT™ Test Solutions | ITS150-HP

150 mm High Power Manual Probe System for accurate High Power measurements up to 10 kV, 600 A

Microscope Mount and Movement

- Stable bridge for high quality optics
- Linear z lift for easy reconfiguration
- 25 x 25 mm air bearing or 50 x 50 mm linear XY movement

Adjustable Platen Height

- Micrometer control for precise adjustment
- 20 mm range for various applications

Probe Platen

- Stable and rigid design
- Supports DC/CV, RF and High Power measurements
- Rectangular adjustments for RF positioners
- Designed for maximum thermal stability

Unique Platen Lift

- Three discrete positions for contact, separation (300 μ m) and safety loading (3 mm)
- Safety lock function at loading position
- "Auto Contact" position with ± 1 μ m repeatability for consistent contact quality

Platen Arc Shield

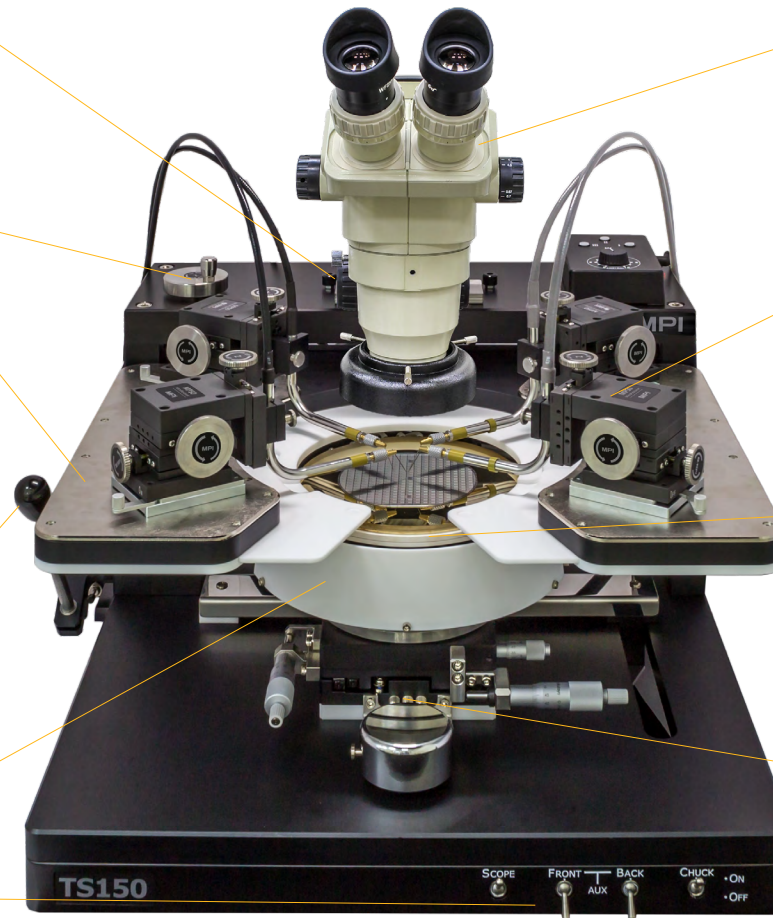
- Designed for safe operation
- Prevents platen high voltage arching from chuck

Front Mounted Vacuum Control

- Easy access
- Clearly marked

Available Options

- Vibration isolation platform
- Vacuum pump and air compressor unit



Microscope and Optics Options

- Various optics options available
- Stereo MPI ST45 or single tube MPI SZ10, MZ12 with up to 12x zoom and 95 mm working distance
- High Power microscopes FS70/PSM-1000
- HDMI cameras, monitor user interface without computer

Positioners and High Power Probes

- Supports up to 4 high current and 8 high voltage positioners
- Various positioners available
- Dedicated Coax and Triax high voltage and high current probe arms (up to 600 A pulse)

Modular Chucks

- Various non-thermal and thermal chucks
- Wide range of temperature up to 300°C
- Thin wafer handling capability
- 10 kV (Coax), 3 kV (Triax)
- Gold plated for low contact resistance
- MPI chuck connectors for safe instrument connection

Chuck XY Stage Movement

- Unique puck controlled air bearing stage for quick single-handed operation
- 180 x 230 mm XY total stage movement
- Resolution < 1.0 μ m (0.04 mils) @ 500 μ m/rev
- Extra wide Y-range for easy loading
- $\pm 5^\circ$ Theta fine adjustment

Note

- Includes low-noise Dark Box with safety interlock, light and EMI shielding

The complete test package includes:

TS150 Manual Test System with puck controlled air-bearing stage

- For high power application up to 10 kV / 600 A
- 180 x 230 mm (7.1 x 9.1 in) XY total stage movement
- 25 x 25 mm micrometer fine stage movement
- ±5 degree fine chuck Theta rotation
- Probe platen ArcShield™ for High Voltage measurements
- Platen lift w/ discrete contact, separation (300 µm) and loading (3 mm) positions for ease of use, safety lock function at loading position
- Dedicated 20 mm fine platen height adjustment
- Stable microscope bridge mount
- Vibration absorbing base
- Integrated service loop for stable XY stage movement
- Include TB900 table, dark box, and interlock for safety operation

150 mm Coax Chuck, non-thermal

- Stainless steel chuck top with vacuum rills
- BNC (female) chuck connection
- 2 m coaxial cable male-male BNC

Air-Bearing Microscope Movement / 25x25 mm

- Precision 25 mm x 25 mm X-Y microscope transport
- Very easy to operate, vacuum fixation with convenient On-Off switch
- 90 degree tilt for easy and safety probe replacement or reconfiguration
- 50mm focus block

ST45 Stereo Microscope with 6.7:1 zoom ratio

- Set of 25x eyepieces for optimal magnification
- Working distance 100 mm, C-mount adapter
- 72 LED ring illumination, four-zone selectable, external remote control
- 100-240V AC, CE

Options depending on the desired application:

- MicroPositioners MP25 for HV probe arms and MP40 with RF probe arms for HC and HP probes
- Probe arms and probes
- Chuck upgrades to HP-Triax and thermal HP-Chucks

Accessories, wafer tweezers, L-key set

